

FORM PTO 1449 (modified)			ATTY DOCKET NO. 2004_0409	SERIAL NO. NEW	10/798396		
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			APPLICANT Setsuo KAJIWARA et al.				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			FILING DATE March 12, 2004		GROUP 1742		
Date Submitted to PTO: March 12, 2004			U.S. PATENT DOCUMENTS				
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
GW	AA	6,001,195	12/1999	Kajiwara et al.			
GW	AB	5,547,633	8/1996	Muddle et al.			
GW	AC	4,919,177	4/1990	Homma			
GW	AD	5,350,468	9/1994	Masumoto et al.			
GW	AE	5,306,363	4/1994	Masumoto et al.			
GW	AF	5,178,689	1/1993	Okamura et al.			
GW	AG	5,069,731	12/1991	Yoshizawa et al.			
GW	AH	5,149,381	9/1992	Grewe et al.			
	AI						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AJ						
	AK						
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
GW	AL	Merriman, A.D., "A Dictionary of Metallurgy", MacDonald & Evans, Ltd, London, page 138, 1958					
GW	AM	Hawley, Gessner G., The Condensed Chemical Dictionary (8 th ed.), New York, Van Nostrand Reinhold Company 1971, pg. 827.					
GW	AN	Abstracts of the Japan Institute of Metals, "Formation Mechanism of Nano-crystal and Tabular Aligned Precipitate in Ti-Ni Sputtered Thin Film", No. 151, p. 165, September 28, 1996					
GW	AO	Kajiwara et al., "Formation of nanocrystals with an identical orientation in sputter-deposited Ti-Ni thin films", Philosophical Magazine Letters, Vol. 74, No. 6, 395-404, December 1996					
EXAMINER	/George Wyszomierski/			DATE CONSIDERED	09/01/2006		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of form with next communication to applicant.